

is performed.

8. (New) The semiconductor-producing/examining device according to claim 5,
wherein on a face of said ceramic substrate, which is the face opposite to the face for

Q2
processing the semiconductor,

the connection between said conductor layer and said external terminal, or

the connection between said another conductor layer and said external terminal

is performed.

IN THE ABSTRACT

Please amend the Abstract on page 42 to read as follows:

ABSTRACT

A semiconductor-producing/examining device that can maintain a preferable connection state for a predetermined period of time and that can easily remove a ceramic substrate from a supporting case. The semiconductor producing/examining device includes a ceramic substrate having a conductor layer formed on the surface thereof or inside thereof and a supporting case. An external terminal is connected to the conductor layer. A connection between the conductor layer and the external terminal is performed such that the external terminal is pressed on the conductor layer or the external terminal is pressed on another conductor layer connected to the conductor layer by using the elastic force and the like of an elastic body.
